Special Issue

Women's Special Issue Series: Metrology

Message from the Guest Editors

Although a range of policy actions have been made to promote gender equality, female representation in STEM areas is still unsatisfactory. The number of male researchers working in STEM is much larger than for women, and this is a constant in countries all over the world. This problem is also evident, of course, in metrology. The inbalance between the number of male and female researchers affects the visibility of the work done by women, who rarely have positions that allow them to appear as individual authors or first authors of scientific articles. This Special Issue aims to give visibility and better dissemination to research works in metrology where the lead author is a woman (i.e., a person who identifies as a woman) or that are completely authored by women. Although we encourage women scientists leading research on metrology to submit an original manuscript to this Special Issue, we want to promote a policy of gender equality; we welcome submissions from all authors, irrespective of the gender identity.

Guest Editors

Prof. Dr. Annalisa Liccardo
Department of Electrical Engineering and Information Technology,
University of Naples Federico II, 80125 Naples, Italy

Prof. Dr. Samanta Piano
Department of Mechanical, Materials and Manufacturing Engineering,
University of Nottingham, Nottingham NG8 1BB, UK

Deadline for manuscript submissions

closed (20 January 2024)

Metrology

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Impact Factor 1.5
CiteScore 2.6

mdpi.com/si/117933

Metrology
Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
metrology@mdpi.com

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Message from the Editor-in-Chief

Metrology draws together researchers from diverse areas of metrology or measurement technology in a wide variety of applications. I encourage you to submit your manuscripts for consideration or publication in the area of measurement engineering, according to the scope of the journal. *Metrology* is supported by our authors and their institutes through low article processing charges (APC) for accepted papers. We hope you will support the journal by becoming one of our authors.

Editor-in-Chief

Prof. Dr. Han Haitjema
Department of Mechanical Engineering, KU Leuven, Celestijnenlaan 300, 3001 Leuven, Belgium

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